






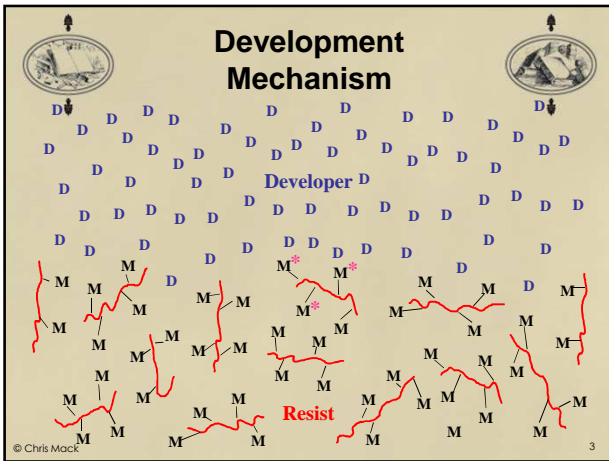
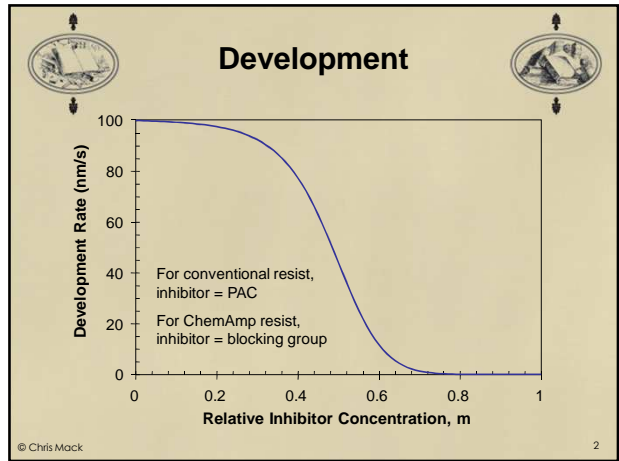
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Lecture 53 Lithography: Resist Development

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- ### Development Mechanism
- Diffusion of developer to resist surface
 - Reaction at resist surface (*rate limiting step*)
 - dominated by the number of exposure events (or amplification events) required to trigger one dissolution event (called *n*, the *dissolution selectivity*)
 - Diffusion of dissolved resist into developer
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Development Mechanism

- Diffusion of Developer to Resist Surface:

$$r_D = k_D (D - D_s)$$

where r_D = rate of diffusion
 k_D = rate constant
 D = bulk developer concentration
 D_s = surface developer concentration

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Development Mechanism

- Reaction at Resist Surface:

$$r_R = k_R D_s P^n$$

where r_R = rate of reaction
 k_R = rate constant
 D_s = surface developer concentration
 P = exposed PAC concentration (or deblocked polymer concentration)
 n = reaction order (dissolution selectivity)

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Development Mechanism

- At steady state:

$$r_D = r_R = r$$

where r = resist (steady state) dissolution rate.

$$k_D(D - D_s) = k_R D_s P^n$$

Now solve for D_s and eliminate from equation.

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Development Mechanism

- Eliminating D_s and solving for r :

$$r = r_{max} \frac{(a+1)(1-m)^n}{a + (1-m)^n} + r_{min}$$

This is called the Mack development model

where r_{max} = maximum development rate
 r_{min} = minimum development rate
 n = dissolution selectivity parameter
 $a = [(n+1)/(n-1)](1-m_{th})^n$
 m_{th} = threshold inhibitor concentration

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Development Model

- Definition of threshold inhibitor concentration, m_{th} :
Value of m at which $d^2r/dm^2 = 0$.

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Development Model

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Development Knee

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Lecture 53: What have we Learned?

- What are the three steps in the Mack kinetic development model used here?
- What development parameter controls the performance of the resist?
- What is the physical meaning of the dissolution selectivity parameter, n ?
- What is the development knee and why is it important?

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